

## PATENT ABSTRACTS OF JAPAN

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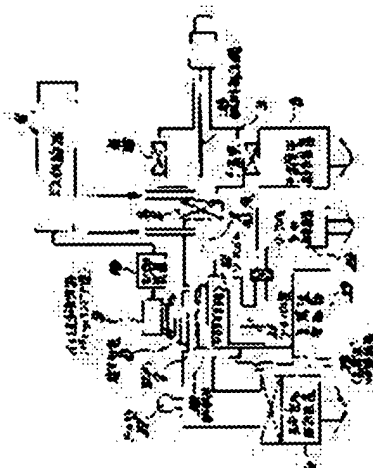
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## (54) METHOD AND APPARATUS FOR VAPOR GROWTH

## (57)Abstract:

PURPOSE: To form a thin film as an atomic layer on a specimen.

CONSTITUTION: In a state that a specimen 7 arranged inside a reaction chamber 1 is exposed to a raw-material gas introduced from a gas supply source 6, the specimen 7 is irradiated with pulse light by using a pulse-light irradiation light source 9. Thereby, a thin film as a monoatomic layer or as a layer of several atoms is grown at each irradiation operation.



## LEGAL STATUS

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